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INFLUENCE OF COPPER VAPORS IN SF_6 PLASMA

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Abstract. In this study a theoretical approach allows estimating the ablation mass flux of copper from a corrected Hertz-Knudsen flux. The influence of the copper vapours coming from the anode electrode to an SF_6 plasma is studied in a simplified 2D configuration. Depending on the plasma pressure an ablation or a diffusion state is considered. The amount of copper versus time is presented. An RMS current I=10kA is applied leading at t=10ms to an amount of copper equal to 0.6mg. The vapours change the plasma properties mainly the electrical conductivity and radiation and so the plasma behaviour. At time t=5ms the electrode erosion leads to a copper plasma. This simple case shows the necessity to well consider the copper erosion in plasma modelling as in High Voltage Circuit Breaker (HVCB) where higher current are considered.

Keywords: Copper ablation, High Voltage Circuit Breaker, Electric arc.

1 1. Introduction

In HVCB modelling, ablation of electrodes is rarely 2 taken into account whereas in reality, at high current it could be an important process. Modelling such ablation is quite complex due to numerous mechanisms 5 involved. In this paper, an approach is proposed to 6 represent this phenomenon. In a first part, the basis 7 of the ablation model are discussed. Then a magneto 8 hydrodynamic model and the specific source terms due q to the ablation are presented. A "simple" geometry is 10 used to test this new model. Results show a strong 11 presence of copper within the plasma even with a 12 small part of the electrode ablated. The vapours 13 should change strongly the properties of the plasma 14 and then the importance of mechanisms involved in 15 the HVCB. 16

17 2. Theory

¹⁸ 2.1. Ablation model

When an electrode is submitted to the heat and radi-19 ation fluxes coming from the arc, its temperature can 20 increase and then ablation occurs. The description 21 of the ablation process is quite difficult to describe 22 23 and depends on the pressure vapor P_{vap} of the ablated metal. In our case, metal is copper. P_{vap} is 24 given in (1). It depends on the surface temperature 25 T_s , the temperature of vaporisation of the metal T_{vap} , 26 the mass of the metal particle m_{Cu} and its heat of 27 vaporisation L_{vap} , k_b is the Boltzmann constant. 28

$$\frac{P_{vap}}{P_0} = \exp\left(\frac{L_{vap} \cdot m_{Cu}}{k_b} \cdot \left(\frac{1}{T_{Vap}} - \frac{1}{T_s}\right)\right) \quad (1)$$

Depending on the pressure of the plasma P_0 two different cases have to be considered:

 \Box Case 1: The "diffusion case" where $\frac{P_{vap}}{P_0} \leq 1$

 \Box Case 2: The "ablation case" where $\frac{P_{vap}}{P_0} > 1$

In the first case, the temperature of the surface T_s is under the temperature of vaporisation of the metal T_{vap} . Then, the surface is in equilibrium with the plasma and metal vapors diffuse from the surface to the plasma. The mass fraction of copper on the surface can be calculated from equation (2). M_{Cu} and M_{Pl} are repectively molar mass of copper and plasma.

$$\omega_{cu} = \frac{P_{Vap}.M_{Cu}}{P_{Vap}.M_{Cu} + (1 - P_{Vap}) \cdot M_{Pl}}$$
(2)

In the second case, an ablation process occurs. Se-41 menov [1] explains that in this situation, a strong flow 42 of copper vapours goes away from the surface and that, 43 close to the surface, the vapour is no more in equilib-44 rium in the plasma. Indeed, a Knudsen layer appears 45 where the distribution function of the vapours is no 46 more Maxwellian. This layer is followed by another 47 one in overpressure (compared with the one of the 48 plasma) but in equilibrium. Semenov [1] has proposed 49 a 1D approach to describe the phenomena of ablation 50 in this context in order to obtain the ablated mass 51 flux $\Phi_{Cu}(kg/(m^2 \cdot s))$ of copper and also the mean 52 velocity of the copper flow in the plasma v_{Cu} . Even if 53 this approach is very interesting, its implementation is 54 difficult. Benilov [2] proposes another approach which 55 consists to estimate the ablation mass flux of copper 56 as proportional to the Hertz-Knudsen flux Φ_{HK} (3) 57

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$$\Phi_{HK} = P_{Vap} \cdot \sqrt{\frac{m_{Cu}}{2\pi k_b T_s}} \tag{3}$$

Then copper mass flux is given by equation (4) where α_v can be calculated from material and plasma data (see [2] for more details).

$$\Phi_{Cu} = \alpha_v \cdot \Phi_{HK} \tag{4}$$

We compared the two approaches which lead for cop-61 per to the same results [3] for the ablation mass flux. 62 Nevertheless, in his article, contrarily to Semenov, 63 Benilov doesn't estimate the velocity of the particles 64 coming inside the plasma. We propose to estimate this 65 velocity from the ablation mass flux using equation 66 (5). $\rho_{Cu}(T_{Vap})$ is the mass density of copper vapour 67 at the temperature of vaporization T_{Vap} . 68

$$v_{Cu} = \frac{\Phi_{Cu}}{\rho_{Cu}(T_{Vap})} \tag{5}$$

⁶⁹ 2.2. The magneto hydrodynamic model

70 2.2.1. geometry

To analyse the results, and to study the influence of
the copper vapours, we have used the geometry given
in Figure 1. The geometry is axisymetric with axis
AI. In the upper part, AB is an electrode considered
as an anode. BC and HI are pressure inlet/outlet,

as an anode. BC and HI are pre
 CDEFGH are walls.

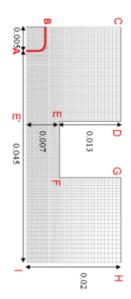


Figure 1. Geometry used for the simulation (dimensions in m).

77 2.2.2. Hypotheses

⁷⁸ We assume that the configuration can be describe in ⁷⁹ two dimensions (2D) with an axis of symmetry. The ⁸⁰ top electrode is pure copper. As the problem is 2D, ⁸¹ a porous electrode located on segment (EE') is used. ⁸² The fluid is assumed to be Newtonian and laminar, the ⁸³ gas is SF_6 with copper (coming from the electrode) and the plasma is assumed to be in Local Thermal Equilibrium (LTE). The problem is transient.

2.2.3. Equations

In order to describe the arc fluid model the Navier Stokes equations are solved coupled with the mass and energy conservation equations. All these equations can be written in the form of the generalized conservation equation (6).

$$a \cdot \frac{\partial}{\partial t}(\rho\phi) + b \cdot \vec{\nabla}(\rho\vec{v}\phi) = \vec{\nabla}(\Gamma\vec{\nabla}(\phi)) + S_{\phi} \qquad (6)$$

For the fluid, the equations solved are mass con-92 servation, momentum equations for axial and radial 93 velocity v_z and v_r , energy conservation for enthalpy h 94 and then temperature T. The equation for the mass 95 fraction of SF_6 , ω_{SF_6} , is solved and mass fraction of 96 copper ω_{Cu} deduced. Thermodynamic and transport 97 properties of pure SF_6 and copper are used and Wilke 98 laws [4] are applied to obtain the mixture properties. 99 Electrical properties of the plasma (current density 100 \vec{i} , magnetic field \vec{B}) are obtained repectively from 101 the equation for electric potential V and potential 102 vector components A_r and A_z . The radiation of the 103 plasma is treated by Discrete Ordinate method on 7 104 bands where mean absorption coefficient of SF_6 and 105 copper have been pre-calculated. This enables to ob-106 tain the radiative flux and its divergence. Additional 107 details on the equations set and boundary conditions 108 can be found in previous papers [5-7]. With copper 109 vapours, specific source terms for ablation model have 110 to be taken into account. Furthermore, the copper 111 vapours coming from the electrode are transported 112 in the plasma. In the real case, they can re-solidify 113 when the gas temperature becomes lower than the 114 one of vaporisation. If this condition occurs during 115 calculation, we assume that copper is re-solidified and 116 that it disappears from the fluid part. The following 117 source terms are then written for ablation model and 118 re-solidification of copper: 119

□ Source term in the equation of mass conservation. ¹²⁰ For the mass conservation source term S_m given in ¹²¹ equation (7) is used in order to take into account the ¹²² exiting vapours at low temperature from a surface ¹²³ S of normal $\vec{e_s}$ close to a cell of volume V_{cell} . Losses ¹²⁴ of copper in the volume are described by the second ¹²⁵ part of the equation. ¹²⁶

$$S_m = \beta \cdot \left[\frac{\Phi_{Cu} \cdot \vec{S}}{V_{cell}}\right] - \alpha \cdot \left[\frac{\omega_{Cu} \cdot \rho_{Cu}(T)}{\Delta t}\right] \quad (7)$$

With $\alpha = 0$ if $T > T_{Vap}$ and 1 otherwise. Δt is 127 the time step of the simulation. β is equal to 1 in 128 the layer close the electrode $\sim 0.1mm$ 0 elsewhere. 129

□ Source terms in momentum equations. It is necessary to take into account the momentum of vapours flowing from the anode surface to the plasma. The source terms of equations (8) and (9) are used. Resolidification of copper leads also to a decrease of momentum in the fluid domain (second part of the equations)

$$S_{v_z} = \beta \cdot \left[(\rho_{Cu}(T_{vap}) \cdot v_{Cu} \cdot \vec{e_s} \cdot \vec{e_z} \right] -\alpha \cdot \left[\omega_{Cu} \cdot \rho_{Cu}(T) \cdot v_z \right]$$
(8)

$$S_{v_r} = \beta \cdot \left[\rho_{Cu}(T_{vap}) \cdot v_{Cu} \cdot \vec{e_s} \cdot \vec{e_r} \right] -\alpha \cdot \left[\omega_{Cu} \cdot \rho_{Cu}(T) \cdot v_r \right]$$
(9)

 \Box Source term for energy equation. Concerning the 130 vapours arriving in the plasma, we assumed that 131 they are pre-heated in the anode sheath by collisions 132 with the electrons and by radiation. This assump-133 tion has a consequence on the energy balance at 134 the anode. This point will be presented in the next 135 paragraph. Then, the energy source term can be 136 estimated from equation (10). h_{mean} is the mean 137 enthalpy of the plasma in the layer close to the 138 electrode. If only one cell is present in the layer (as 139 in our geometry) this is the enthalpy of the plasma 140 in this cell. It depends on temperature T, pressure 141 P and mass fraction ω_{SF_6} of SF_6 . 142

$$S_{nrj} = \beta \cdot \left[\frac{\Phi_{Cu} \cdot S}{V_{cell}} \cdot [h_{mean} - h(T_{vap}) + L_{vap}] \right]$$
$$-\alpha \cdot \left[\omega_{Cu} \cdot \rho_{Cu}(T) \cdot [h(T_{plasma} - h(300K) + L_{vap}]] \right]$$
(10)

143 2.2.4. Modelling of the anode

The anode is made of copper. Properties function of temperature for thermal conductivity, mass density and specific heat are used [8]. We don't take into account the liquid copper movements but liquefaction of copper is taken into account by adapting the specific heat close to the liquefaction temperature T_{liq} . Radiation emissivity of copper given by [9] is used.

In the electrode, electric potential and vector po-151 152 tential equations are solved. The source term of Joule effect is taken into account. In order to model the 153 anode, we use the assumption proposed by Lowke and 154 Tanaka [10]: a small layer of 0.1mm with an electric 155 conductivity of 10^4 S/m is used in the sheath. The 156 energy flux at the anode surface is given in equation 157 (11) where $q_{cond, plasma}$ is the conduction flux from 158 the plasma, q_{rad} the radiation flux estimated from 159 DOM method, W_{Cu} the electron work function of 160 the copper. No voltage in the sheath is considered 161 and depending on the case it can be as positive as 162 negative. In the energy flux on the anode, the heating 163 of vapours coming from anode to plasma is taken into 164 account. On the surface, this flux is balanced by the 165 conduction flux towards the anode. 166

$$q_{anode} = q_{cond,plasma} + \frac{\vec{J} \cdot \vec{e_s}}{k_b \cdot e} \cdot (T_s - T_{plasma}) + \vec{J} \cdot \vec{e_s} \cdot (W_{s,Cu}) - q_{rad} - \Phi_{Abl} \cdot [h(T_{vap}) - h_{mean} + L_{vap}]$$
(11)

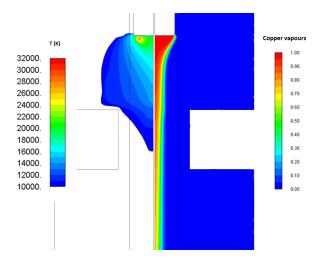


Figure 2. Temperature and copper mass fraction for time t=5ms.

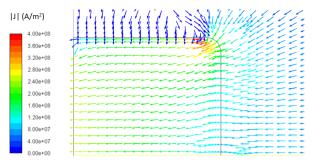


Figure 3. Current density vector close to the electrode for time t=5ms.

2.2.5. Parameters for the calculation

The problem is solved by Ansys Fluent software. Specific User Defined Subroutines have been developed for taking into account plasma characteristics [7] and the interaction with the anode. The imposed current density is a half wave sinus curve, with a period of 10ms, and a maximum intensity equal to 10kA. The time step for the calculations is $\Delta t = 10 \mu s$.

3. Results

3.1. Temperature and copper mass fraction

Temperature and mass fraction fields obtained at time 177 t=5ms are presented in figure 2. Concerning mass 178 fraction, we can observe that, at this time, the whole 179 core of the plasma is composed of pure copper. The 180 temperature is quite high with a maximum around 181 30kK. One can observe that this maximum is located 182 out of the axis, close to the corner of the electrode. 183 This effect is due to the current path which occurs 184 preferentially on the electrode corner. To verify this 185 point, the current density vector is plotted in figure 186 3. Where the current density is maximum, the Joule 187 effect is high leading to the out of axis maximum 188 of temperature. This shows the importance of well 189 describing the current path from the electrode to the 190 plasma. 191

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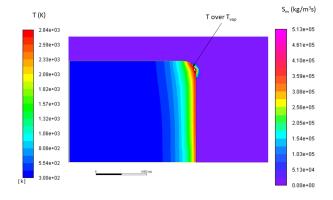


Figure 4. Temperature in the electrode (left) and mass source term due to copper ablation (equation (7)) at t=5ms.

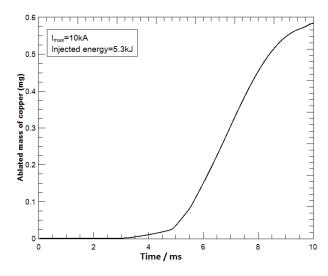


Figure 5. Ablation of copper material with time t.

¹⁹² 3.2. Ablation process

Another interesting field to plot is the mass source 193 term due to copper ablation. It is plotted in figure 194 (4) with the temperature in the anode. At this time, 195 the temperature is high close to the electrode surface 196 in contact with the plasma and propagation within 197 the electrode can be observed. Nevertheless, only 198 the corner of the electrode is over the vaporisation 199 temperature which leads to ablation (case $2 \frac{P_{vap}}{P_0} > 1$). 200 The amount of copper coming from the ablation is then 201 located very close to this corner. Nevertheless it is 202 interesting to observe that the copper has propagated 203 in the whole core of the plasma, changing its properties 204 compared to pure SF_6 . 205

The calculated case leads to an energy injected of 5.3kJ. For this energy the amount of ablated copper with time is plotted in figure 5. A total amount of 0.6mg was obtained. Of course this quantity should increase with the current intensity value.

4. Conclusions

In this paper we presented a model in SF_6 plasma taking into account the ablation of a copper electrode.

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For the ablation process, two main cases must be dis-214 tinguished : One corresponding to a diffusion process 215 and another corresponding to a "convective" ablation. 216 We detailed how to take into account the amount of 217 copper linked with hydrodynamic equations. A tran-218 sient case with a sinus half current wave at 10kA was 219 presented. This case shows the capacity of the model 220 to describe the ablation process. Even if a small part 221 of the electrode is ablated, the plasma totally burns 222 in a copper medium without any SF_6 in its core. This 223 means that in a real HVCB configuration, the fact 224 to consider the copper ablation should change the 225 properties of the plasma and then the models predic-226 tions. This effect will be more important increasing 227 the current value. 228

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